

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	Group Art Unit: 2822
Koichiro TANAKA et al.)	Examiner: Mary A. Wilczewski
Serial No. 10/749,505)	
Filed: January 2, 2004)	
For: LASER IRRADIATION METHOD,)	
METHOD FOR MANUFACTURING)	
SEMICONDUCTOR DEVICE, AND)	
LASER IRRADIATION SYSTEM)	

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AMENDMENT

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Please consider the following amendments and remarks in connection with the above-identified application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 14 of this paper.